

Status of high gradient studies at Uppsala

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Outline

- In-SEM Field Emission Studies
- Dark current at Xbox RF test stand
- Summary

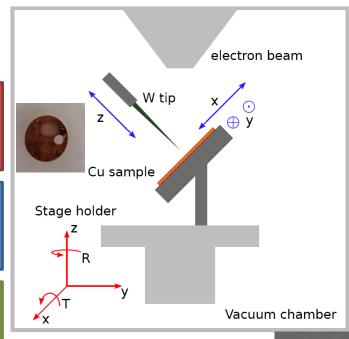


Stage

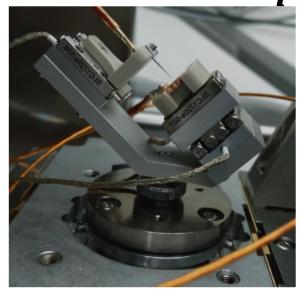
W tip, radius of curvature 5 μm nm precision piezo-motors

Environmental SEM
Field emitting gun, 10-30 kV
Vacuum ~7×10⁻⁵ mBar

Keithley 6517a Electrometer
FE currents from sub-pA to mA
Applied V = up to 1 kV, 50 Hz



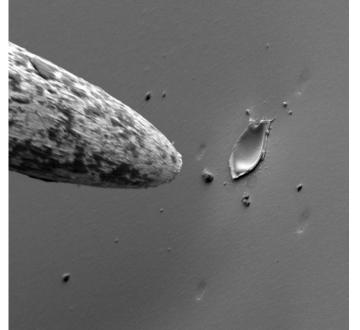
In-SEM Setup



Typical gap distance → 700 nm

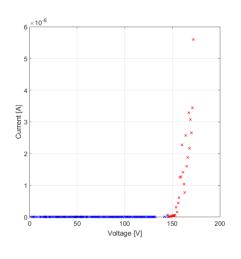
Surface search procedure:

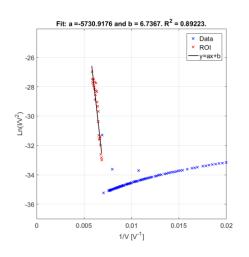
Low voltage, approach surface in steps (2 nm) while measuring current until threshold breech (done 2 times just left and right to the area-of-interest)



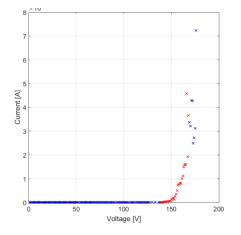


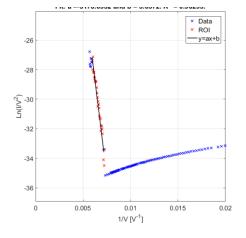
$\textit{I-V curves} \\ \textit{Fitting of } \beta \textit{ parameter} \\$







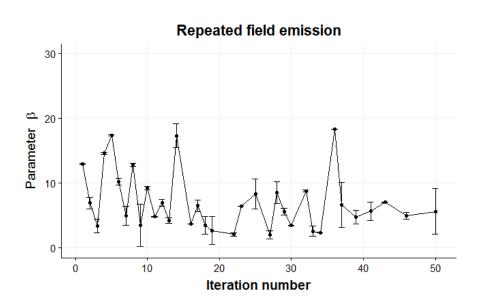




$$\beta = 17.6$$

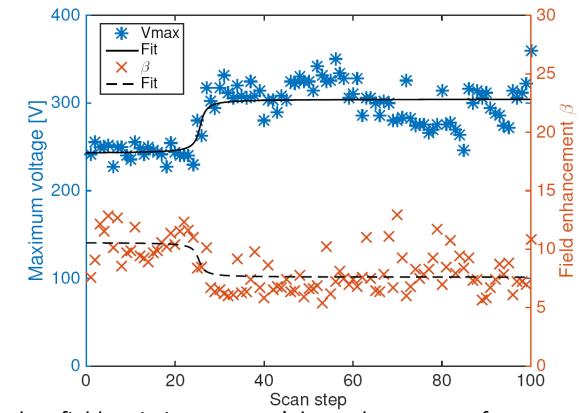


Repeated scan β parameter





Repeated scan \(\beta \) parameter



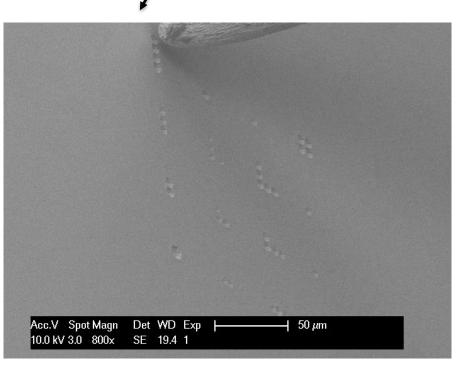
Let's look at field emission currents' dependence on surface morphology -> need higher resolution SEM scans



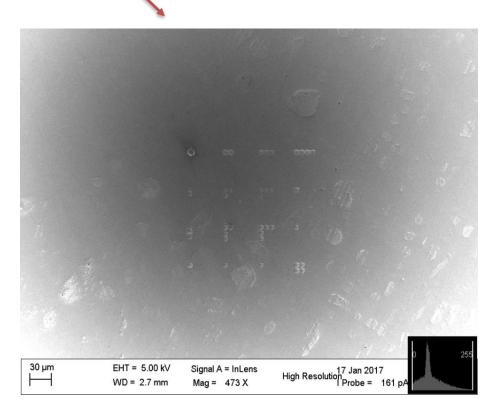
Experimental procedure

Marking an area in ESEM (for easy recognition)

Move sample to HR-SEM for surface microscopy of the area



Areas are marked in ESEM before initial surface analysis Here: $150 \times 150 \, \mu m$; $5 \mu m$ depth



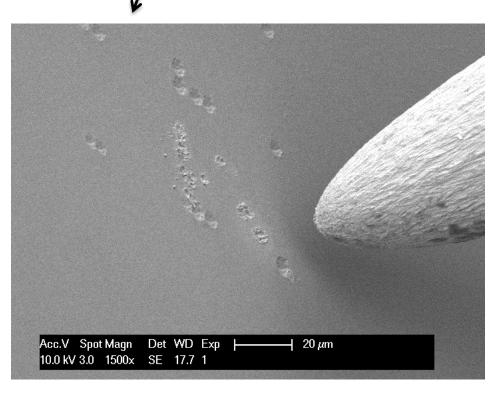
High-resolution SEM Zeiss LEO 1550 FEG

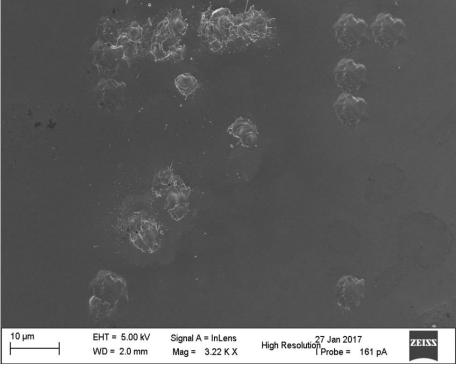


Experimental procedure

Move back to ESEM for FE experiments

Move sample back to HR-SEM for post-experiment surface microscopy







Results of high res surface scan contrast change



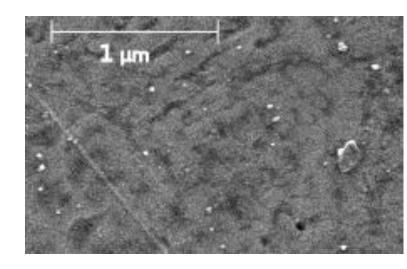
"FE" areas

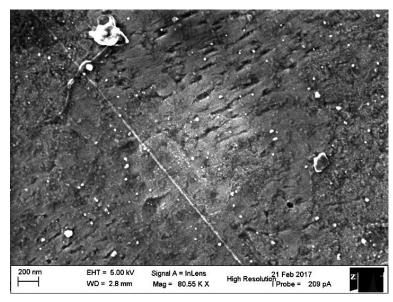
before

and



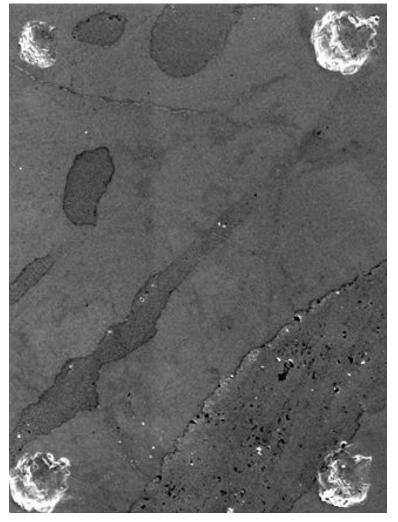
after

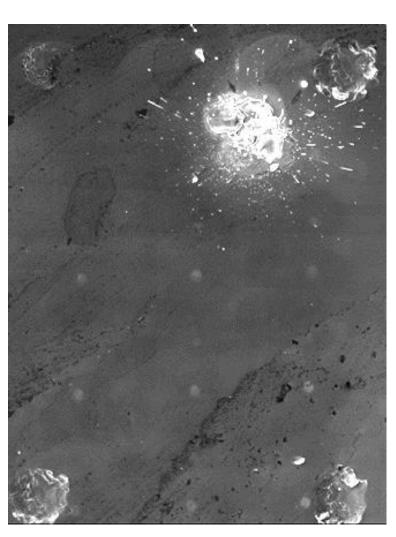






Before After







Surface composition XPS analysis

We found no correlation to surface morphology

-> field emission currents do not so much depend on surface morphology, but rather on something else such as surface chemistry.

We know that we affect the surface, but what happens?

Adding X-ray photoelectron spectroscopy information

Steps *):

- 1. Markings
- 2. XPS analysis and Ar sputtering
- 3. HR-SEM observation
- 4. FE experiments
- 5. Final HR-SEM observation
- 6. Final XPS analysis

MARKINGS DONE ON 2017/11/23 Soft Cu Samples

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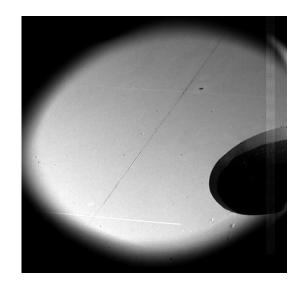
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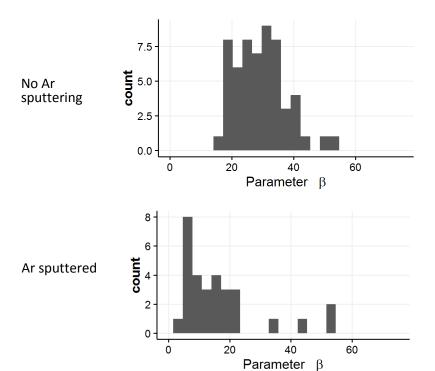


^{*)} Between steps the sample is placed in a vacuum desiccator

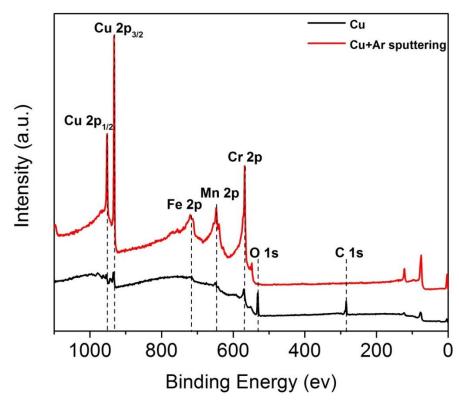


Surface composition Effect of argon sputtering

- After Ar sputtering O and C peaks disappear.
- C contamination on surface equals to a thickness of 3.6 nm on top of Cu (rough estimate)



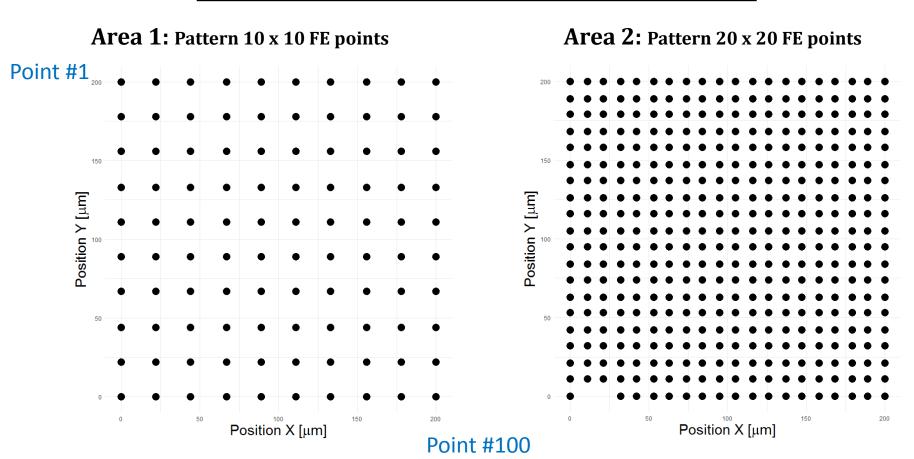
Calculated beta parameter with argon cleaning Voltage scans at several location



XPS analysis works only on large areas, $> 50 \mu m$



Experimental area: 200 μm x 200 μm in both cases

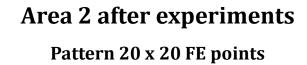


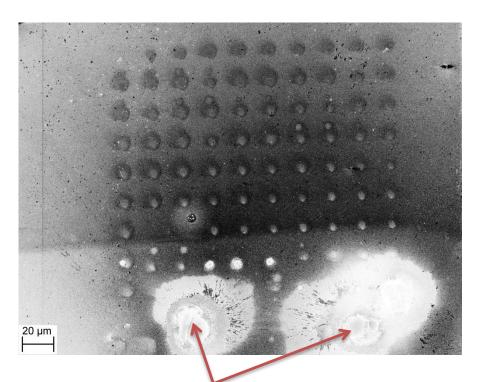


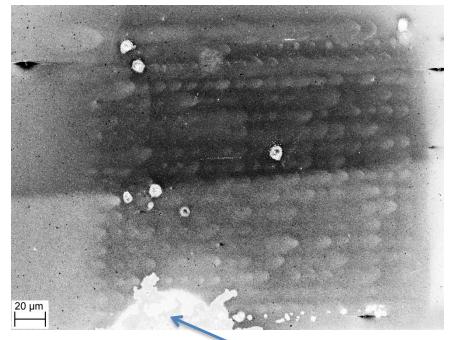
Experimental area: 200 μm x 200 μm in both cases

Area 1 after experiments

Pattern 10 x 10 FE points







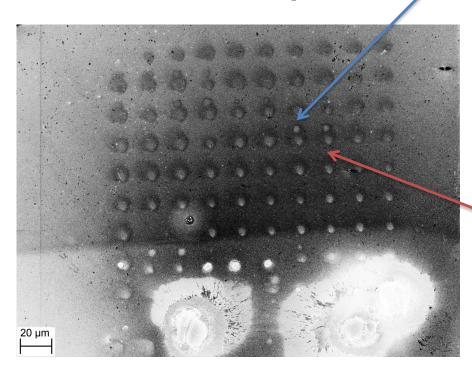
Breakdown at the end of scan

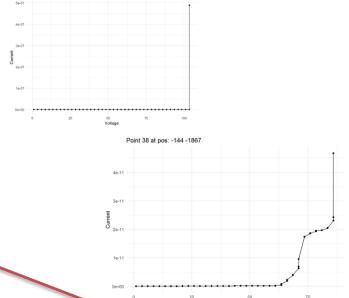


Experimental area: 200 μm x 200 μm in both cases

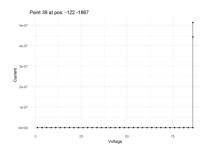
Area 1 after experiments

Pattern 10 x 10 FE points





Double-spots I-V curves have sometimes different shape



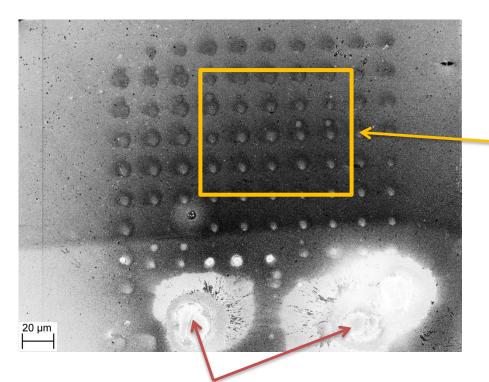


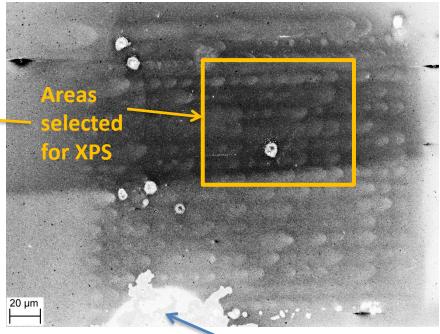
Experimental area: 200 μm x 200 μm in both cases

Area 1 after experiments

Pattern 10 x 10 FE points

Area 2 after experiments
Pattern 20 x 20 FE points



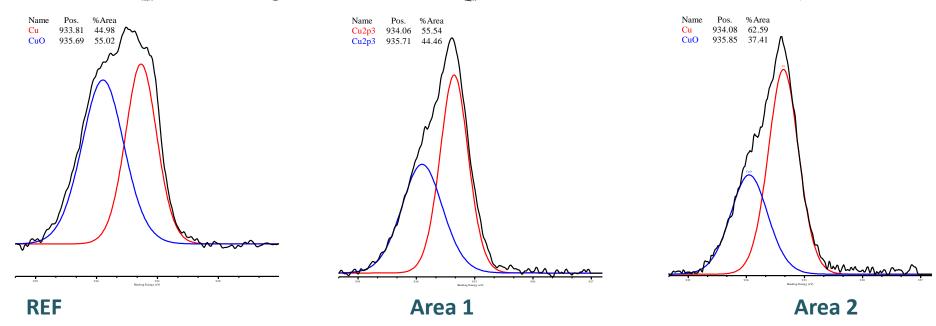


Breakdown at the end of scan



Surface composition XPS results

The contrast change is related to a change of oxidation state of the Cu surface atoms

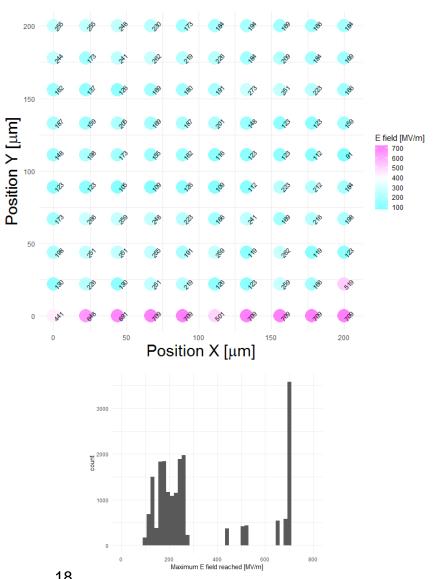


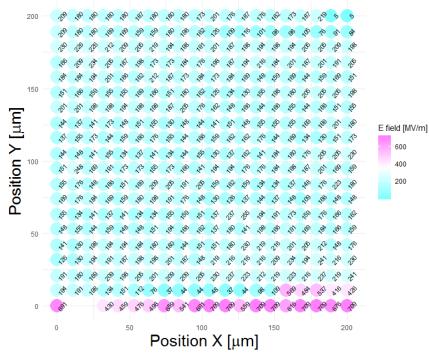
Area	Pattern density	Cu [%]	CuO [%]	CuO thickness
Reference	0	44.98	55.01	1.13 nm
Area 1	10 x 10 FE points	55.54	44.46	0.82 nm
Area 2	20 x 20 FE points	62.59	37.41	0.65 nm

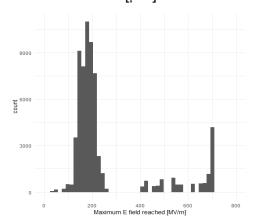
What is the mechanism of the CuO removal? We still do not know ...



Max field reached during FE scans

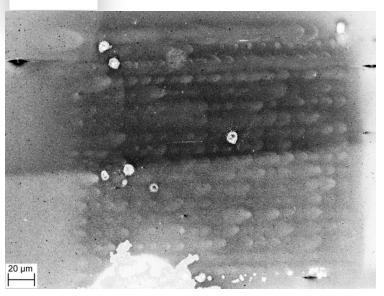


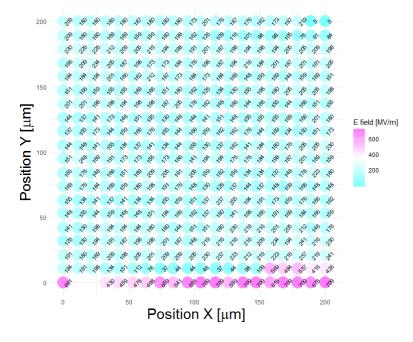


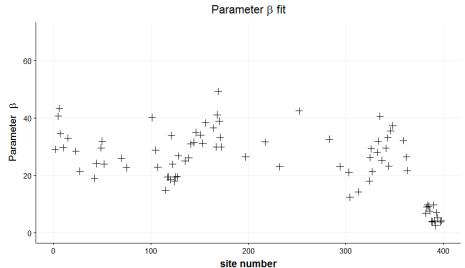




Beta parameter during FE scans

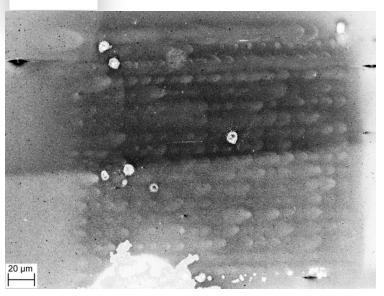


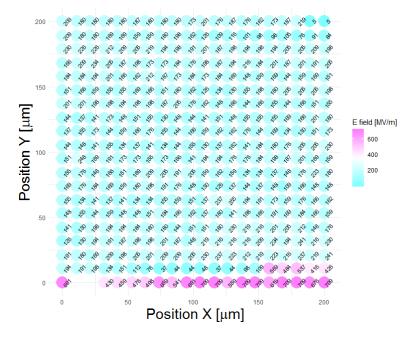


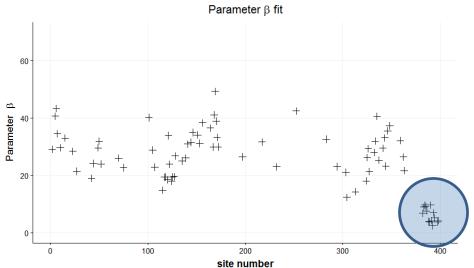




Beta parameter during FE scans

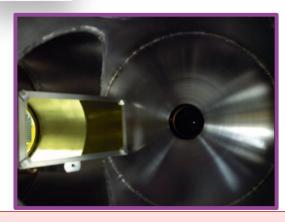








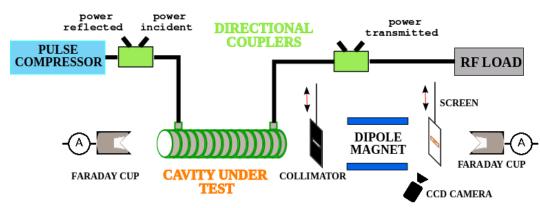
Uppsala/CLIC X-band Spectrometer (UCXS) Currently at "XBox1" 12GHz 50 MW RF test stand @CERN

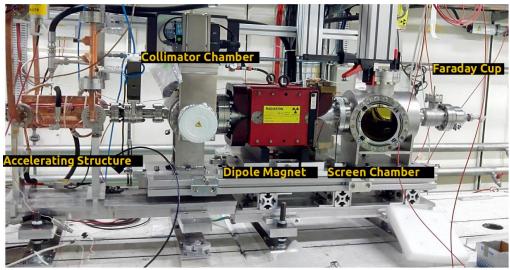


Screen (100x50x0.5 mm YAG:Ce) linear actuator (fully retractable) 30 degrees angle w.r.t. the beam axis 2M pixel, 50fps camera with focuser



Collimator (5 mm tungsten plate) linear actuator (retractable), place for two patterns, presently: **pin-hole** 0.5mm and **slit** 10x0.5mm





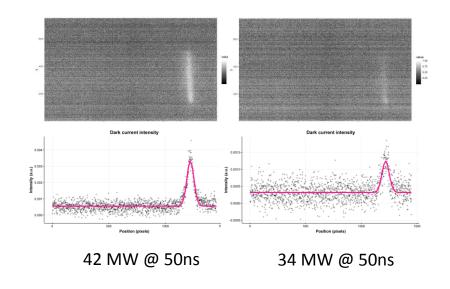
Energy resolution with dipole magnet

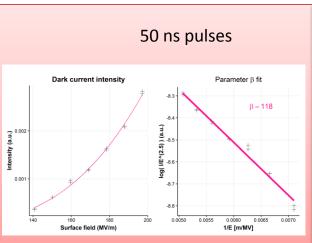
Maximum expected electron energy ~20MeV Rel. energy spread (single slit) 10% - 25% Full energy coverage with magnetic field scan

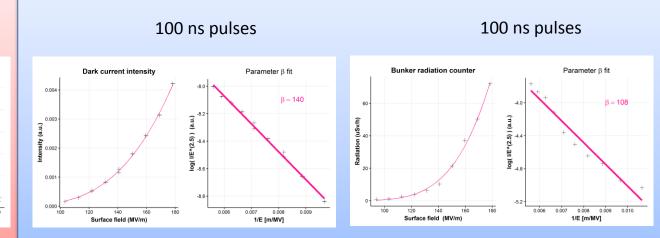


Power scans at different pulse length

Recent dark current measurements after transfer to XBox1



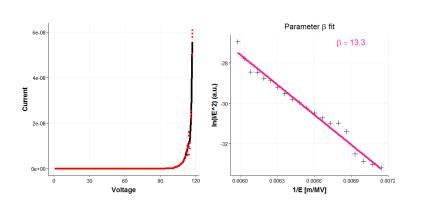


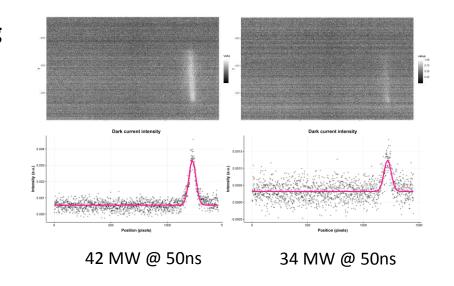


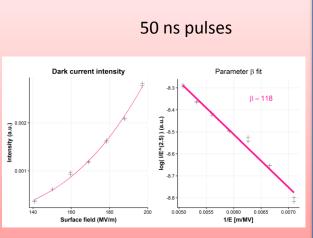


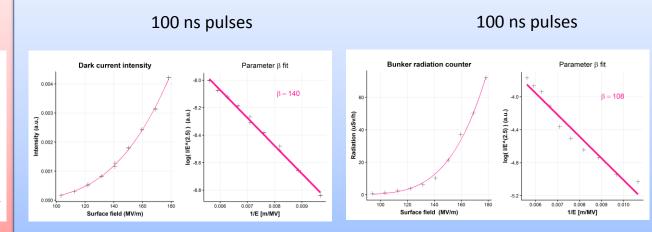
Recent dark current measurements after transfer to XBox1

Effective beta parameter rather high comparing to measured during in-SEM experiments





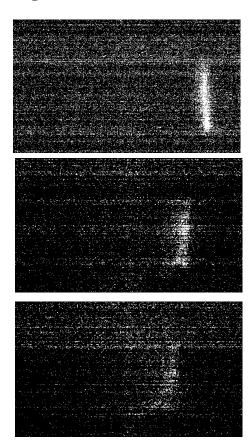


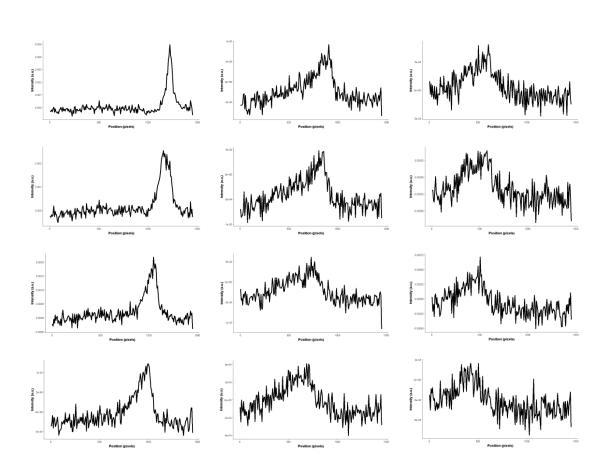




Dark current measurements magnet scans

Magnet scans at constant RF power example for 40 MW @ 50ns







Dark current studies <u>Simulations</u>

Dark current simulations by Thomas G. Lucas (CST Studio 3D electromagnetic simulation)

+

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Spectrometer simulation by Daniel Persson (GEANT4 Monte Carlo physics simulation suite)

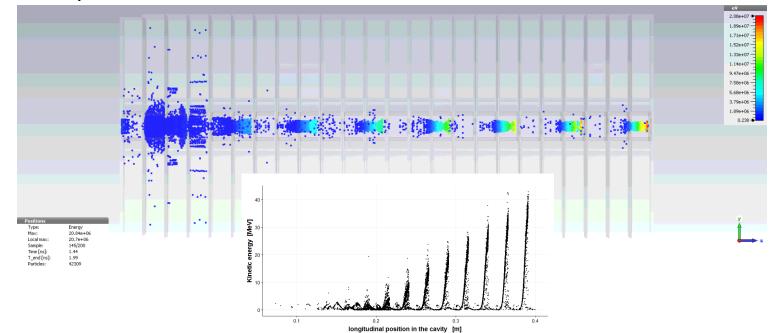
= dark current studies in XBox1 with the spectrometer

Example questions to address:

Can we detect turn-on signature of single emitter?

Can we detect hot spots and their location?

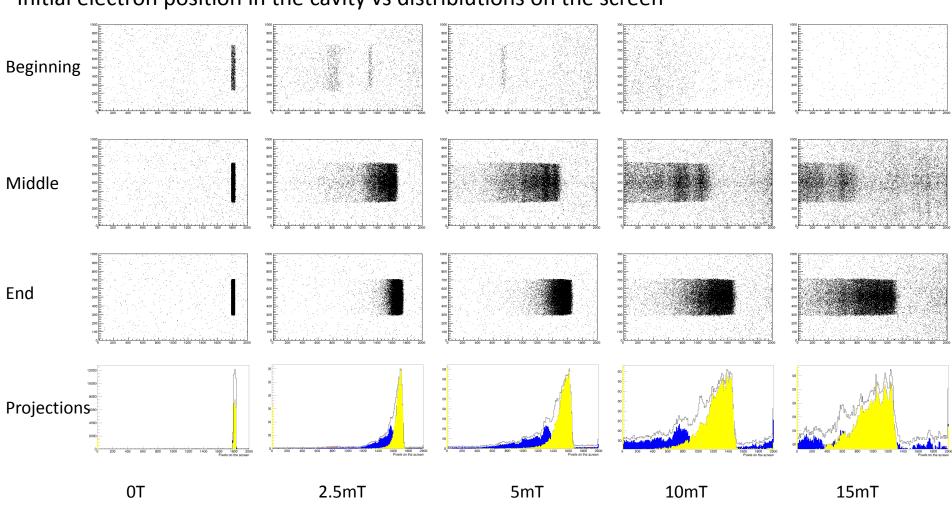
What sensitivity do we need for this?





Dark current studies <u>Simulations</u>

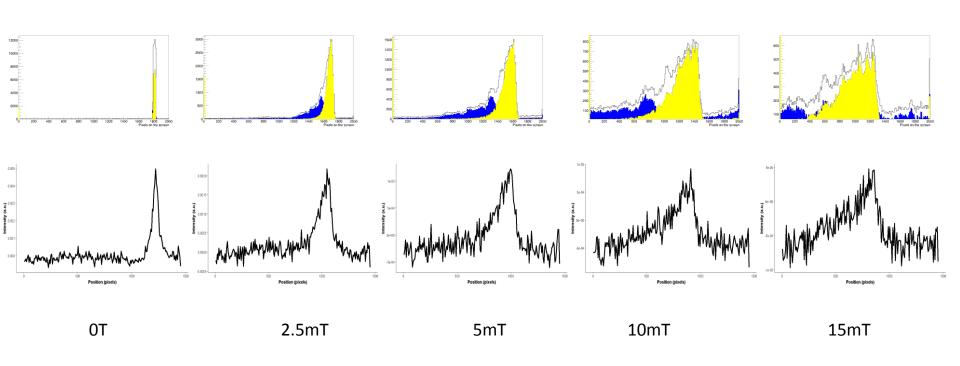
Example: Magnet scans
Initial electron position in the cavity vs distribiutions on the screen





Dark current studies <u>Simulations</u>

Matching simulation with experimental data





Summary and outlook

In-SEM setup

- Correlate surface features to FE-scans
 - We see effect of the FE scans directly after, however spots disappear after days
 - No indication of other, long lasting, surface changes (like e.g. melting)
- Quantify surface changes with XPS
 - Requires large surface affected by our experiments
 - Relative concentration of CuO had decreased after FE
- Working on mechanism to explain the change in oxidation state of surface Cu

Xbox experiments status

- Experiments with focus on dark current at XBox1
 - Power scans
 - Magnet scans
 - Study dark current behavior (trends and before/after breakdowns)
- High effective beta parameter measured during power scans
- Xbox setup simulations: spectrometer simulation with RF simulation of CLIC cavityongoing
- Dark current changes with temperature
- Need to improve the setup with focus on dark current for further studies



Next:



Thank you for attention